

www.fablab.umd.edu

A cutting-edge complex for nano- and microfabrication

Supporting research, education, and technology development

Open to and serving the University of Maryland, industry, government labs, and external academic and nonprofit organizations

Potassium-ion batteries enhanced by coated microspheres

Nanotechnology starts and flourishes with making things at the nanoscale-from fabricating prototype materials and devices for R&D, to piloting the means to manufacture key nano components, microsystems, and products made from them. The FabLab provides the needed equipment and skilled personnel to support academic, corporate and government partners, as well as University of Maryland researchers.

The FabLab is part of the Maryland NanoCenter, a partnership of the A. James Clark School of Engineering and the College of Computer, Mathematical and Natural Sciences at the University of Maryland.

The FabLab supports the Maryland NanoCenter's mission of providing cutting-edge nanotechnologies and services for engineering and science researchers in academia, industry and government; developing future professionals who have hands-on experience in nanotechnology; and promoting a vibrant nanotech economy in the state of Maryland through interactions with established and emerging companies.

FOR INFORMATION, PLEASE CONTACT:

DR. NAM KIM DIRECTOR, FABLAB (301) 405-6664 nsk0248@umd.edu PROF. SANG BOK LEE DIRECTOR, NANOCENTER (301) 405-7096 slee@umd.edu





ULTRASMALL

SEMICONDUCTOR DEVICES

MOLECULAR ELECTRONICS

THIN FILM TRANSISTORS

DISPLAYS

ENERGY STORAGE

SOLAR CELLS

SENSORS

MEMS DEVICES

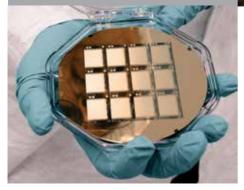
CHEM-BIO SENSORS

CELL-BASED MICROSYSTEMS

QUANTUM DOTS

NANO-ROBOTICS

www.fablab.umd.edu



THE FABLAB IS PART OF THE MARYLAND NANOCENTER, A PARTNERSHIP OF:



A. JAMES CLARK SCHOOL OF ENGINEERING

COLLEGE OF COMPUTER, MATHEMATICAL, & NATURAL SCIENCES



SUPPORTED IN PART BY:





FULL SERVICE MICRO- AND NANOFABRICATION

OPEN TO INTERNAL AND EXTERNAL USERS

FEATURED TOOLS

Maskless aligner system

Atomic layer deposition

Ebeam lithography(<20 nm) and ICP etching

Deep reactive ion etching XeF2 etching E-beam & sputter deposition Advanced plasma etching Wire bonding

CHARACTERIZATION TOOLS Environmental SEM with EDS

Four point resistivity & Hall effect

Raman & FTIR

Stress measurement BET porosimetry

Spectroscopic ellipsometry

